SOFTWARE-DEFINED EVEN ENGINEER SOFTWARE-DEFINED ENGINEER STATES OF THE SOFTWARE-DEFINED ENGINEER SOFTWARE-DEFINED ENGINEER

kate temkin / michael ossmann supercon 2019

Katherine/Kate Temkin (@ktemkin):

- software lead hardware hacker at Great Scott Gadgets
- open-source-tool-builder
- educational (reverse) engineer

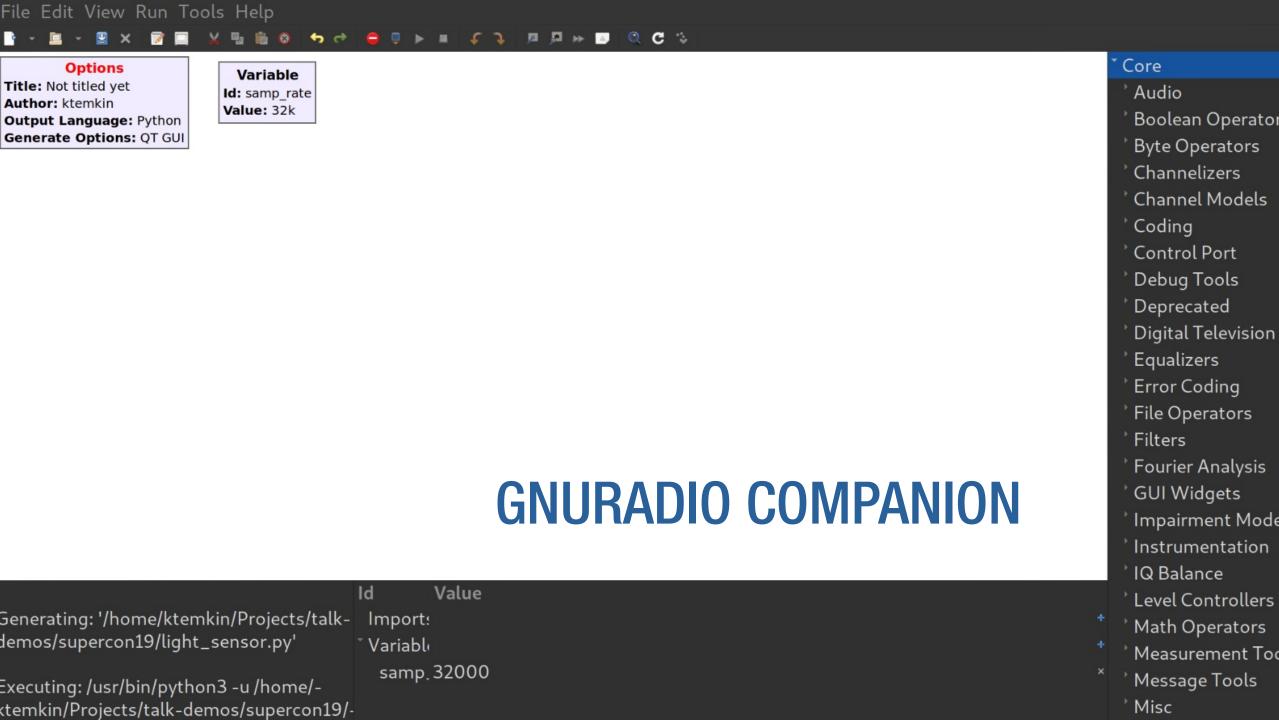
Michael Ossmann (@michaelossmann):

- founder of Great Scott Gadgets
- Software-Defined Radio enthusiast, educator
- hardware designer

software defined: specialized stuff made without specialized hardware

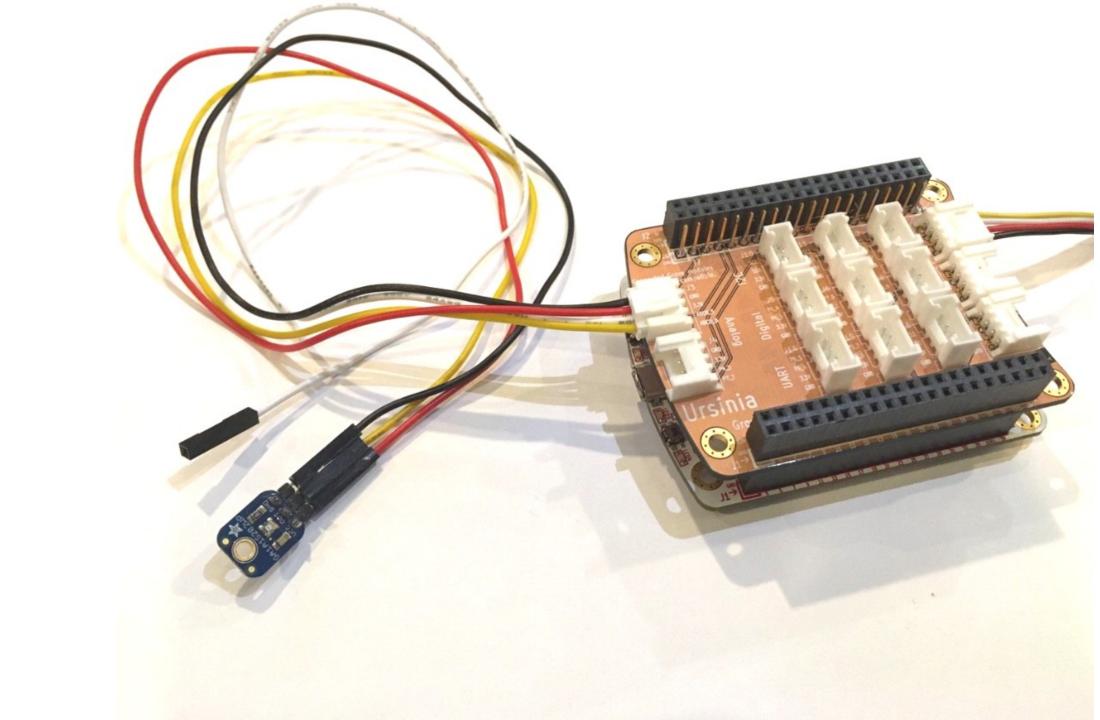
SOFTWARE DEFINED RADIO



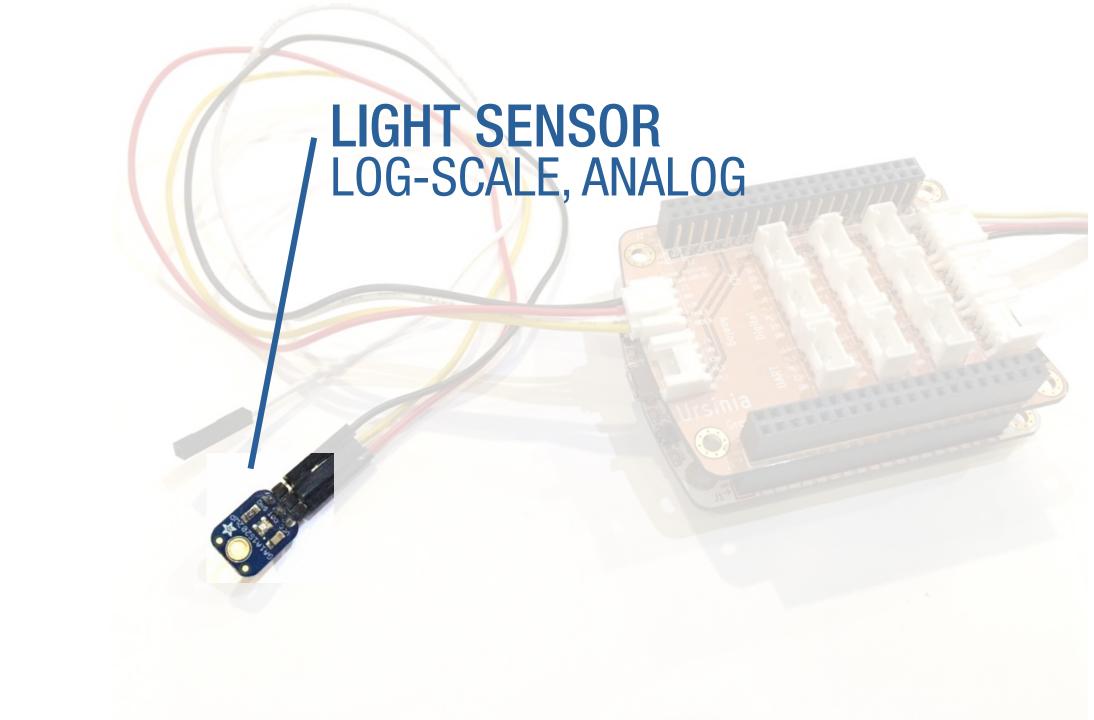


[time domain demo]

[frequency domain demo]







[interfacing demo]

Options

Title: Not titled yet
Output Language: Python

Generate Options: QT GUI

Variable

Id: samp_rate
Value: 1k

I2C Register Source
Sample Rate (sps): 1k
Device Address: 8
Register number: 1
Register size (bytes): 1
Register full scale: 100

Sample Signedness: Unsigned

Prelude:

Prelude script:

Rational Resampler Interpolation: 48
Decimation: 1
Taps:
Fractional BW: 0

Taps:
Fractional BW: 0

QT GUI Sink

Name:

FFT Size: 1.024k

Center Frequency (Hz): 0

Bandwidth (Hz): 1k

Update Rate: 10

Multiply Const Constant: 50m **Audio Sink Sample Rate:** 48 kHz

QT GUI Range

Id: gain

Default Value: 50m

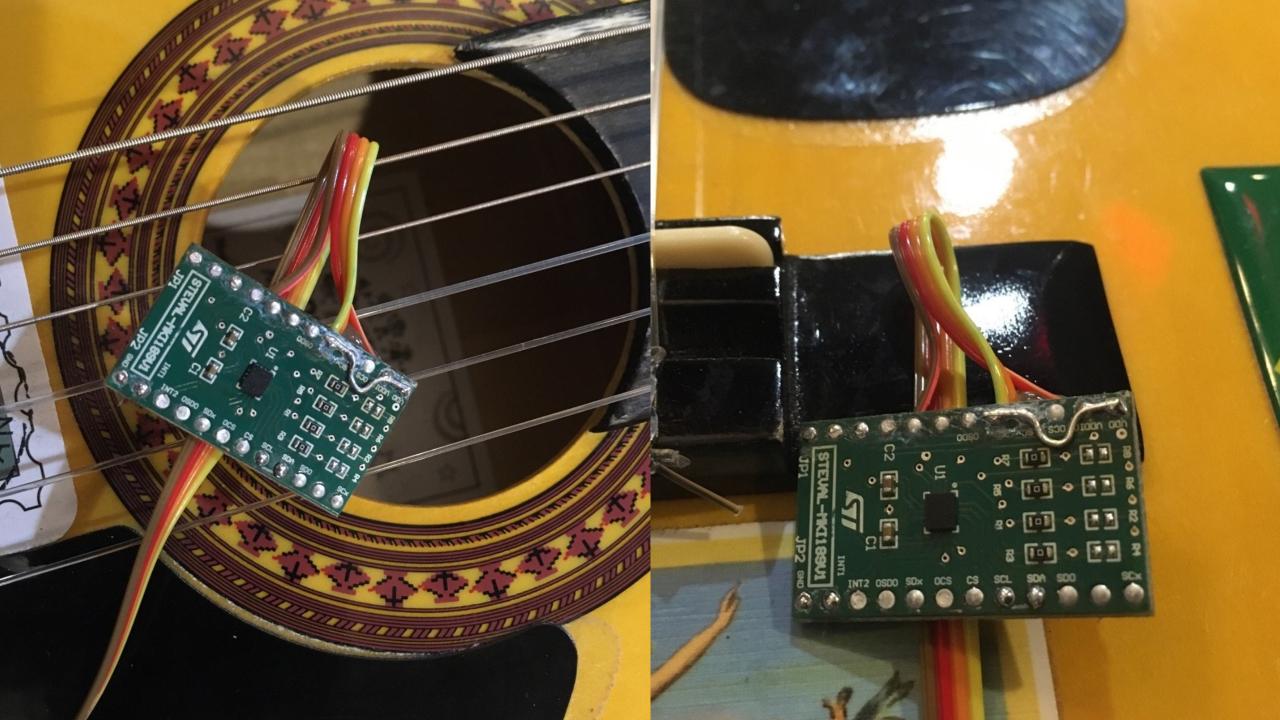
Start: 0 Stop: 1 Step: 10m [more sensors]



LSM6DSM ACCELEROMETER



LSM6DSM ACCELEROMETER MICROPHONE



Options

Title: Accelero...r Amplifier

Author: mossmann

Description: Use a... pickup. **Output Language:** Python **Generate Options:** QT GUI

Variable

Id: samp_rate
Value: 6.621k

QT GUI Range

Id: post

Default Value: 1

Start: 0 **Stop:** 11.1 **Step:** 100m

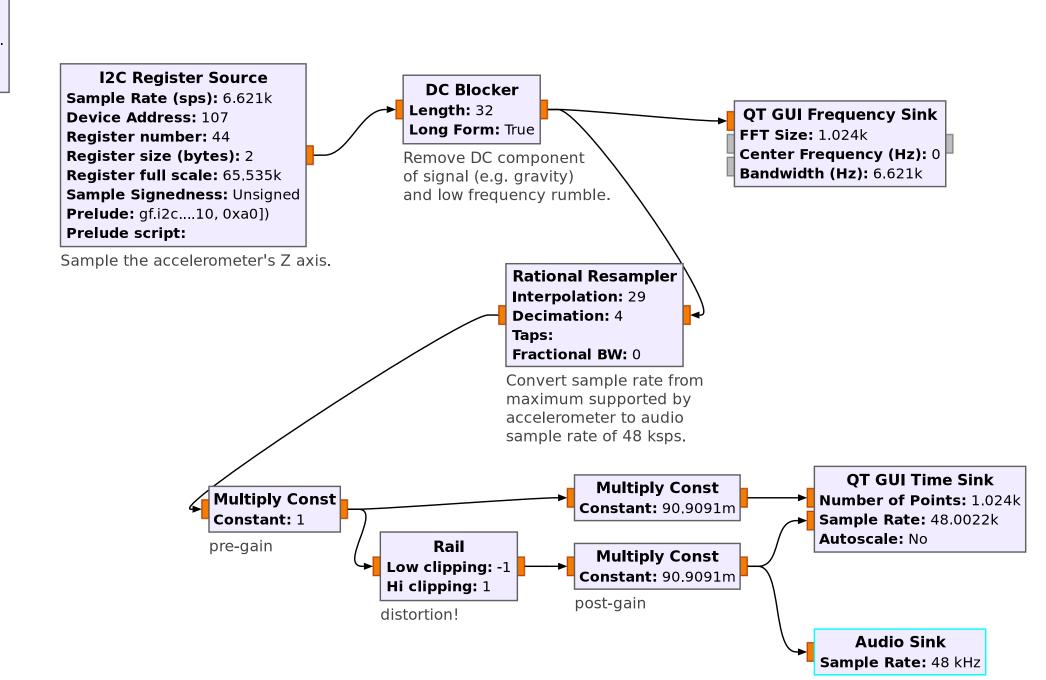
QT GUI Range

Id: pre

Default Value: 100m

Start: 0 **Stop:** 11.1 **Step:** 100m

These go to eleven.



Sonic Nirvana: Using MEMS Accelerometers as Acoustic Pickups in Musical Instruments

By Rob O'Reilly, Alex Khenkin, and Kieran Harney

Introduction

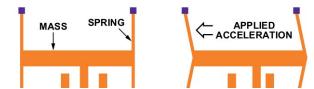
MEMS¹ (microelectromechanical systems) technology builds on the core fabrication infrastructure developed for silicon integrated circuits. Micromechanical structures are created by etching defined patterns on a silicon substrate to form sensor elements or mechanical actuators that can move fractions of a micron. Pressure sensors, one of the first high volume MEMS applications, now monitor pressure in hundreds of millions of engine manifolds and tires; and MEMS accelerometers have been used for over 15 years for airbag deployment, rollover detection, and automotive alarm systems.

MEMS accelerometers² are also used for motion sensing in consumer applications, such as video games and cell phones. MEMS micromirror optical actuators are used in overhead projectors, HDTVs, and digital theater presentations. In recent years, MEMS microphones³ have begun to proliferate the broad consumer market, including cell phones, Bluetooth headsets, personal computers, and digital cameras.

This article describes some of the key technologies deployed in MEMS accelerometer products and discusses how this technology can bring a new dimension to acoustic transducers.

MEMS Accelerometer Technology

The core element of a typical MEMS accelerometer is a moving beam structure composed of two sets of fingers: one set is fixed to a solid ground plane on a substrate; the other set is attached to a known mass mounted on springs that can move in response to an applied acceleration. This applied acceleration (Figure 1) changes the capacitance between the fixed and moving beam fingers.⁴



formed from single-crystal silicon, or from polysilicon that is deposited at very high temperatures on the surface of a single-crystal silicon wafer. Structures with very different mechanical characteristics can be created using this flexible technology. One mechanical parameter than can be controlled and varied is spring stiffness. The mass of the sense element and the damping of the structure can also be modified by design. Sensors can be produced to measure fractions of one *g* or hundreds of *g*'s with bandwidths as high as 20 kHz.



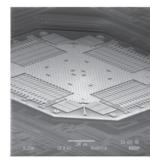


Figure 3. ADXL202 ±2 g accelerometer.

The MEMS sensing element can be connected to the conditioning electronics on the same chip (Figure 3) or on a separate chip (Figure 4). For a single-chip solution, the capacitance of the sense element can be as low as 1 to 2 femtofarads per g, which equates to measurement resolution in the attofarad range! In a two-chip structure, the capacitance of the MEMS element must be high enough to overcome the parasitic capacitance effects of the bond wires between the MEMS and the conditioning ASIC (application specific integrated circuit).⁵

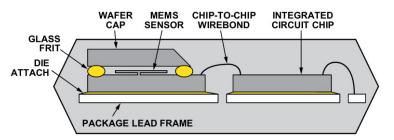


Figure 4. Cross-section of a typical two-chip accelerometer.

Accelerometers as Vibration Measurement Sensors

The concept of using vibration sensing transducers as acoustic

All code & demos are online!

https://github.com/greatscottgadgets/greatfet https://github.com/ktemkin/presentations

QUESTIONS?

Options

Title: Light Sensors

Output Language: Python **Generate Options:** QT GUI

Variable

Id: samp_rate

Value: 1k

